Docket No.: 49657-961

## **PATENT**

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Kenji ITOGA, et al.

Serial No.: 09/769,490

Filed: January 26, 2001

Customer Number: 20277

Confirmation Number: 55

Group Art Unit: 2882

Examiner: C. Kao

X-RAY EXPOSURE APPARATUS, X-RAY EXPOSURE METHOD, X-RAY MASK For: X-RAY MIRROR, SYNCHROTRON RADIATION APPARATUS, SYNCHROTRON RADIATION METHOD AND SEMICONDUCTOR DEVICE

## **PETITION FOR EXTENSION OF TIME**

Mail Stop RCE Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

It is respectfully requested that the time for response to the Office Action dated September 16, 2003, now due to expire December 16, 2003, be extended for two (2) months and set to expire on February 17, 2004 (February 16, 2004 being a US government holiday). Please charge the extension fee of \$420.00 to Deposit Account No. 500417. Please charge any additional fees or credit any overpayment to Deposit Account No. 500417.

02/19/2004 MAHMED1 00000042 500417 09769490

02 FC:1252

420.00 DA

Respectfully submitted,

MCDERMOTT, WILL & EMERY

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Date: February 17, 2004